HALO QRP

Trace-Level Low-Pressure Moisture Analyzer

GASES & CHEMICALS CEMS	ENERGY	ATMOSPHERIC	SEMI & HB LED	SYNGAS	LAB & LIFE SCIENCE

Designed for trace level moisture analysis in low pressure (<50 Torr) applications, the HALO QRP offers:

- Moisture detection at partial pressure of 1 µTorr and below
- Absolute accuracy and excellent precision
- Wide dynamic range—over four orders of magnitude
- Low cost of ownership and operational simplicity
- Clean technology—no external calibration gases required
- Compact analyzer footprint, also available as OEM module for equipment/system integration

Protect Your Process with the HALO QRP

Modern semiconductor deposition processes—from low-temperature epitaxy to MOCVD—operate routinely at chamber pressures far below atmosphere and approach the single-digit torr range. At the same time, process temperatures are continuously decreasing. Under these conditions, residual moisture in the chamber poses a significant threat to process quality and production yields.

Tiger Optics' new HALO QRP is optimized to operate under these low-pressure conditions and deliver

exact and reliable real-time measurement to verify moisture residue in, for example, the load lock, transfer and process chambers before H_2O contaminants compromise the subsequent process step. Based on Tiger Optics' proven Continuous-Wave Cavity Ring-Down Spectroscopy (CW-CRDS) technology, the HALO QRP sets new standards in ease-of-use and measurement precision for this application, and operates at chamber pressures as low as 1 Torr.



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Performance, H ₂ O Detection		
Operating range	0 – 12 mTorr _{pp}	
	(1200 ppm @ 10 Torr)	
Detection limit (LDL,	1 µTorr _{pp}	
24 h peak-to-peak variation)	(see chart below for ppb units)	
Sensitivity (3o)	0.7 μTorr _{pp}	
	(see chart below for ppb units)	
Precision (1 σ , greater of)	\pm 1% or 1/3 of Sensitivity	
Accuracy (greater of)	± 5% or 1/2 of LDL	
Speed of response	1 to 2 min (if not flow-limited)	
Environmental conditions	10°C to 40°C	
	30% to 80% RH (non-condensing)	
Storage temperature	-10°C to 50°C	

Gas Handling	System	and	Conditions*
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Wetted materials	316L stainless steel
	(optional Hastelloy [®])
	10 Ra surface finish
Gas connections	1/4" male VCR inlet and outlet
	with manual shut-off valves
Leak tested to	1 x 10 ⁻⁹ mbar l / sec
Inlet pressure ⁺	1 – 100 Torr (standard)
	1 – 1000 Torr (optional)
Outlet pressure	<20 mTorr (0.027 mbar)
Sample gases§	N_2 , H_2 , He, HCl, and Cl_2
Gas temperature	Up to 60°C (in detection cell)

*Vacuum source required

[†]Pressure requirements for moisture measurement – for gas purge in standby mode, inlet pressure limit is 15 psig (1500 Torr) [§]HCl and Cl₂ sample gases may require Hastelloy[®] cell, please contact us for more information.

Contact us for additional analytes and matrices. U.S. Patent # 7,277,177

Dimensions	H x W x D [in (mm)]
Standard sensor	8.73 x 8.57 x 23.6 (222 x 218 x 599)
Sensor rack	8.73 x 19.0 x 23.6 (222 x 483 x 599)
(fits up to two sensors)	
Weight	
Standard sensor	30 lbs (13.6 kg)
Electrical	
Alarm indicators	2 user programmable
	1 system fault
	Form C relays
Power requirements	90 – 240 VAC, 50/60 Hz
Power consumption	40 Watts max.
Signal output	Isolated 4-20 mA per sensor
User interfaces	5.7" LCD touchscreen
	(display-less version optional)
	10/100 Base-T Ethernet
	802.11g Wireless (optional)
	RS-232







